



Information and Control Korea TC Chapter

Meeting Summary and Minutes

Korea Standards Summer Meetings

Friday, July 18, 2025

3:00 PM – 5:00 PM (KST)

SEMI Korea office, Seoul / OVTCCM (hybrid)

TC Chapter Announcements

Next TC Chapter Meeting

November 27, 2025, OVTCCM.

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Chulhong Ahn (SK hynix), Hyungsu Kim (Doople), Kelvin Lee (Lam Research)

SEMI Staff: Natalie Shim, Seohyeong Bae (SEMI)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
BISTelligence	Kim	Charlie	Samsung Electronics	Choi	Jinhyeok
<i>Cimetrix</i>	<i>Kim</i>	<i>Anderson</i>	<i>SCREEN</i>	<i>Nishimura</i>	<i>Takayuki</i>
<i>Cimetrix</i>	<i>Ryu</i>	<i>Ian</i>	SEMI Korea	Bae	Seohyeong
Doople	Kim	Hyungsu	SEMI Korea	Shim	Natalie
<i>KSIA</i>	<i>Seong</i>	<i>Jihye</i>	SK hynix	Ahn	Chulhong
<i>Lam Research</i>	<i>Lee</i>	<i>Jerrad</i>	Tokyo Electron	Im	ByoungMin
Linkgenesis	Cha	Kyoungwan	<i>Tokyo Electron</i>	<i>Kang</i>	<i>Daniel</i>
Linkgenesis	Chung	MinGyu	<i>Wonik IPS</i>	<i>Kim</i>	<i>Sehoon</i>
Miracom	Kim	KyeongTai	<i>Wonik IPS</i>	<i>Park</i>	<i>Jungjin</i>
Miracom	Lim	Youngshin	Global ZEUS	Kim	Namjin

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None		

Table 3 TC Chapter Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	



Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
None		

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Ratification Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>ISC A&R Action</i>	<i>A&R Forms</i>
None			

Note 1: **Passed** Ratification ballots will be submitted to SEMI publication for final processing.

Note 2: **Failed** Ratification ballots were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 6 Activities Approved by the GCS between meetings of the TC Chapter

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

Table 7 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 8 Authorized Ballots

<i>#</i>	<i>When</i>	<i>TF</i>	<i>Details</i>
None			

Table 9 SNARF(s) Granted a One-Year Extension

<i>#</i>	<i>TF</i>	<i>Title</i>	<i>Expiration Date</i>
None			

Table 10 SNARF(s) Cancelled

<i>#</i>	<i>TF</i>	<i>Title</i>
None		

Table 11 Standard(s) to receive Inactive Status

<i>Standard Designation</i>	<i>Title</i>
None	



Table 12 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None		

Table 13 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None		

1 Welcome, Reminders, and Introductions

Chulhong Ahn (SK hynix) called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues, and holding meetings with international attendance were reviewed. Attendees introduced themselves.

- Attachment:**
1. Required Meeting Elements March 2024
 2. Meeting Agenda_I&C_TC_July18_2025

2 Review of Previous Meeting Minutes

- Motion:** Approve the minutes with correction
By / 2nd: Hyungsu Kim (Doople) / Jinhyeok Choi (Samsung Electronics)
Discussion: None
Vote: 11-Y 0-N. Motion passed.

- Attachment:** 3. KR I&CC 33rd_minutes

3 Liaison Reports

3.1 I&C China TC Chapter

Natalie Shim (SEMI Korea) reported for the I&C China TC Chapter. Of note:

3.1.1 Meeting Information

- Last Meeting: April 8, Hybrid
- Next Meeting: TBD

3.1.2 Ballot Results

- Doc. 7139, Line-Item Revisions to E40-1218, Standard for Processing Management and E40.1-1218, Specification for SECS-II Protocol for Processing Management passed with a technical change.
- Doc. 7140, Line-Item Revisions to E94-0819R, Specification for Control Job Management and E94.1-0819R, Specification for SECS-II Protocol for Control Job Management (CJM) passed with a technical change.

3.1.3 Please find the attached file for details of TF activities.

- Attachment:** 4. China I&C Committee Chapter Liaison Report - April 2025 v1



3.2 I&C Japan TC Chapter

Nishimura Takayuki (SCREEN) reported for the I&C Japan TC Chapter. Of note:

3.2.1 Meeting Information

- Last Meeting: April 18, SEMI Japan Office / OVTCCM (hybrid)
- Next Meeting: October 21, SEMI Japan Office / OVTCCM (hybrid)

3.2.2 Ballot Results

- Doc. 7330, Line-Item Revision to SEMI E178-0120, Guide for EDA Freeze Version passed.

3.2.3 Authorized Activities

- SNARF 7354, Line-Item Revision to SEMI E170-0520, Specification for Secured Foundation of Recipe Management System (Sforms) and SEMI E170.1-0520, Specification for SECS-II Protocol for Secured Foundation of Recipe Management System has been authorized.

3.2.4 Authorized Ballots

- Doc. 7354, Line-Item Revision to SEMI E170-0520, Specification for Secured Foundation of Recipe Management System (Sforms) and SEMI E170.1-0520, Specification for SECS-II Protocol for Secured Foundation of Recipe Management System has been authorized to proceed in cycle 7, 2025.
- Doc. 7334, Line-Item Revision to SEMI E174-0819, Specification for Wafer Job Management (WJM) has been authorized to proceed in cycle 5 or later, 2025.

3.2.5 Please find the attached file for details of TF activities.

Attachment: 5. JA_I&C_Liaison_2025_May_Ver1

3.3 North America TC Chapter

Natalie Shim (SEMI Korea) reported for the North America TC Chapter. Of note:

3.3.1 Meeting Information

- Last Meeting: June 4, SEMI HQ (Milpitas)
- Next Meeting: October 8, SEMICON West

3.3.2 Leadership Changes

3.3.2.1 Fab & Equipment Computer and Device Security (CDS) Task Force

- Alan Weber (Cimetrix) was appointed as co-leader.

3.3.2.2 Equipment Data Publication (EDP) TF

- Alan Weber (Cimetrix) was appointed as co-leader.

3.3.3 Ballot Results

3.3.3.1 Three ballots failed.

- Doc. 7178, Revision to SEMI E164-0414 (Reapproved 0721), Specification for EDA Common Metadata
- Line-item 1 and 2 in Doc. 7321A, Line-Item Revision to SEMI E120-0922 (Reapproved 0823), Specification for the Common Equipment Model (CEM), SEMI E120.2-0823 Specification for Protocol Buffers for Common Equipment Model (CEM), SEMI E125-0923 Specification for Equipment Self Description (EqSD), SEMI E125.2-0923, Specification for Protocol Buffers for Equipment Self Description (EqSD), SEMI E132-0624



Specification for Equipment Client Authentication and Authorization, SEMI E132.2-0624, Specification for Protocol Buffers for Equipment Client Authentication And Authorization (ECA), SEMI E134-0624, specification for Data Collection Management, SEMI E134.2-0624, Specification for Protocol Buffers of Data Collection Management, and SEMI E179-0624, Specification for Protocol Buffers Common Components

- Doc. 7348, Reapproval of SEMI E54.23-0520, Specification for Sensor/Actuator Network Communications for CC-LINK® IE

3.3.3.2 Two ballots passed.

- Line Item 1 in Doc. 7270, Line-Item Revision to SEMI E151-1211 (Reapproved 0517), Guide for Understanding Data Quality
- Line-Item 1 and 2 in Doc. 7311A, Line-Item Revision to SEMI E191-1024, Specification for Computing Device Cybersecurity Status Reporting and SEMI E191.1-1024, Specification for SECS-II Protocol for Computing Device Cybersecurity Status Reporting

3.3.3.3 One ballot passed with editorial changes.

- Doc. 7347, Reapproval of SEMI E54.18-0914 (Reapproved 0420), Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pump Device

3.3.4 Activities Authorized by GCS between Meetings

- SNARF XXXX, Revision to Add a New Subordinate Standard, Specification for Transforming Non-E142 Xy Coordinates to SEMI E142-0125, Specification for Substrate Mapping was approved.
- SNARF 7357, New Standard, Specification for Failure Analysis Reporting was approved.

3.3.5 Authorized Activities

3.3.5.1 16 ballots were authorized to proceed in cycle 6, 7, 2025.

- Doc. 6743C, Revision to SEMI E95-1101, Specification for Human Interface for Semiconductor Manufacturing Equipment
- Doc. 6926A, New Standard, Specification for Equipment Operator Access Management and Monitoring
- Doc. 7178A, Revision to SEMI E164-0414 (Reapproved 0721), Specification for EDA Common Metadata
- Doc. 7190, Line-Item Revision to SEMI E54.19-1018, Specification for Sensor/Actuator Network for Mechatrolink
- Doc. XXXX, Reapproval of SEMI E175, Specification for Subsystem Energy Saving Mode Communication (SESMC)
- Doc. 7345, Line-Item Revision to SEMI E90-0624, Specification for Substrate Tracking and SEMI E90.1-0624 - Specification for SECS-II Protocol Substrate Tracking
- Doc. 7344, Line-Item Revision to SEMI E192-0121, Guide for Equipment Adoption Criteria for GEM and GEM-Related Standards
- Doc. 7321A, Line Item Revision to SEMI E120-0922 (Reapproved 1224), Specification for the Common Equipment Model (CEM), SEMI E120.2-1224 Specification for Protocol Buffers for Common Equipment Model (CEM), SEMI E125-1224, Specification for Equipment Self Description (EqSD), SEMI E125.2-1224, Specification for Protocol Buffers for Equipment Self Description (EqSD), SEMI E132-0624, Specification for Equipment Client Authentication and Authorization, SEMI E132.2-1224, Specification for Protocol Buffers for Equipment Client Authentication And Authorization (ECA), SEMI E134-1224, Specification for Data Collection Management, SEMI E134.2-1224, Specification for Protocol Buffers of Data Collection Management, and SEMI E179-1224, Specification for Protocol Buffers Common Components
- Doc. XXXX, Line-Item Revision to SEMI E30-0125, Specification for the Generic Model For Communications and Control of Manufacturing Equipment (GEM) SEMI E30-0125 (Technical Revision), SEMI E30.1-0217 (Reapproved 0423) Specification for Inspection and Review Specific Equipment Model (ISEM)

- Doc. XXXX, Line-Item Revision to SEMI E40-0324, Standard for Processing Management and SEMI E40.1-1218 (0324) Specification for SECS-II Protocol for Processing Management
- Doc. XXXX, Line-Item Revision to SEMI E87-0225, Specification for Carrier Management (CMS) and SEMI E87.1-0225, Provisional Specification for SECS-II Protocol for Carrier Management (CMS)
- Doc. XXXX, Line-Item Revision to SEMI E90-0624, Specification for Substrate Tracking and SEMI E90.1-0624, Specification for SECS-II Protocol Substrate Tracking
- Doc. XXXX, Line-Item Revision to SEMI E142-0225, Specification for Substrate Mapping, SEMI E142.1-0225, Specification for XML Schema for Substrate Mapping, SEMI E142.2-1016 (0225), Specification for SECS II Protocol for Substrate Mapping, SEMI E142.3-1016 (0225), Specification for Web Services for Substrate Mapping, SEMI E142.4-1022 (0225), Specification for SECS II Protocol for Substrate Mapping Using Item Transfer
- Doc. XXXX, Revision to Add a New Subordinate Standard: Specification for Transforming Non-E142 XY Coordinates to SEMI E142-0125: Specification for Substrate Mapping
- Doc. 7346, Line-Item Revision to SEMI E54.23-0520, Specification for Sensor/Actuator Network Communications for CC-Link®IE
- Doc. 7355, Reapproval of SEMI E54.22-0914, Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pressure Gauges

3.3.6 Please find the attached file for details of TF activities.

Attachment: 6. NA IC Liaison Report 2025-5_v2

3.4 I&C Taiwan TC Chapter

Natalie Shim (SEMI Korea) reported that there was no official report from Taiwan.

3.5 SEMI Staff Report

Natalie Shim (SEMI Korea) gave the SEMI Staff Report. Of note:

3.5.1 SEMICON Upcoming Events

- SEMICON India: September 1-3, New Delhi
- SEMICON Taiwan: September 10-12, Taipei
- SEMICON West: October 7-9, Phoenix
- SEMICON Europa: November 18-21, Munich
- SEMICON Japan: December 17-19, Tokyo

3.5.2 Global Standards Summit (GSS) 2025

- The Second Global Standards Summit (GSS) will be held at SEMICON WEST 2025. It is to identify standards-critical areas and work towards an industry standardization strategy for the next 3- and 7-year time horizons. The summit will continue discussion on standards-critical topics covered in GSS 2024, as well as new topics needing standards.

3.5.3 Critical Dates for SEMI Standards Ballots

- Ballot for cycle 9 has been changed. See <https://www.semi.org/en/Standards/Ballots>

3.5.4 Style Manual Revision 10 is being reviewed with the ISC regulations Subcommittee.

3.5.5 All SEMI Standards Task Forces shall use Connected@SEMI for managing TF activities and storing documents.



Attachment: 7. Staff_HQ Report June 2025 v4.2

4 Ballot Review

None

5 Subcommittee and Task Force Reports

None

6 Old Business

None

7 New Business

An internal seminar on packaging automation trends is scheduled for September 4. The seminar was organized to address the emerging needs for standardization in backend automation. As most members are frontend engineers, the seminar is intended to help them understand backend automation and to discuss plans and potential items for backend automation standards.

8 Next Meeting and Adjournment

The next meeting is scheduled for Thursday, November 27, 2025, via OVTCCM. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: 17:00.

Respectfully submitted by:

Seohyeong Bae

Coordinator

SEMI Korea

Phone: 82.2.531.7899

Email: sbae@semi.org

Chulhong Ahn (SK hynix), Hyungsu Kim (Doople), Kelvin Lee (Lam Research)

Minutes tentatively approved by:

Chulhong Ahn (SK hynix), Co-chair	<Date approved>
Hyungsu Kim (Doople), Co-chair	<Date approved>
Kelvin Lee (Lam Research), Co-chair	<Date approved>



Table 14 Index of Available Attachments#1

<i>Title</i>	<i>Title</i>
1. Required Meeting Elements March 2024	5. JA_I&C_Liaison_2025_May_Ver1
2. Meeting Agenda_I&C_TC_July18_2025	6. NA IC Liaison Report 2025-5_v2
3. KR I&CC 33rd_minutes	7. Staff_HQ Report June 2025 v4.2
4. China I&C Committee Chapter Liaison Report - April 2025 v1	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.